

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant :	Masaharu Nagai et al.	Art Unit :	1756
Serial No. :	10/694,986	Examiner :	Daborah Chacko Davis
Filed :	October 29, 2003	Conf. No. :	5334
Title :	METHOD FOR REMOVING RESIST PATTERN AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE		

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO ACTION OF OCTOBER 3, 2006

Please amend the above-identified application as follows:

Amendments to the Claims begin on page 2.

Remarks begin on page 8.